

# Device and Circuit Techniques for Emerging Non-Volatile Memories

## Project Description

### 1 Objective and Significance

The traditional memory technologies, e.g. SRAM, DRAM, and Flash memory, played a very important role in the development of modern computing system and portable multimedia device industries. However, the further scaling at 32nm technology node and below is facing significant technical difficulties, such as large process variations, high leakage power consumption, increased capacitive coupling between adjacent cells, and the device endurance and retention issues [1, 2].

In recent years, significant efforts and resources have been put on the researches and developments of **emerging non-volatile memory (NVM) technologies** that combine attractive features such as scalability, fast read/write, negligible leakage, and non-volatility. Multiple promising candidates, such as Phase-Change RAM (PCRAM), Magnetic RAM (MRAM), Resistive RAM (RRAM), and Memristor, have gained substantial attentions and are being actively pursued by industry [1, 3].

Here, we propose a three-year project. The main objective is to investigate modeling and design techniques for emerging NVMs in order to enable the massive production and to accelerate the commercialization of these emerging memory technologies. The proposed program makes the following major contributions.

- **Developing device models:** The device models for emerging non-volatile memories (NVMs) will be developed to fill the gap between process development and circuit design society.
- **Proposing novel circuits solutions:** Based on the unique device characteristics of NVMs, the proposed circuit schemes could benefit from the advantages and make up the shortfalls of NVMs.
- **Integrated educational plan:** The educational plan will enhance the existing standard curricula by integrating new course modules on emerging NVMs to complement and upgrade the core device and circuit design courses, and bring the awareness of emerging memory technologies into the circuit design and computer architecture community through tutorials and workshops.

The proposed work will initiate a novel research direction in memory design by integrating NVM devices into the standard memory design flow, inventing novel array structure and circuit techniques, and investigating the impact to future computing system. The work will support the deployment of modern microprocessor and embedded system design that use emerging NVM technologies. The proposed research will provide a complementary perspective to the existing computing system research.

### 2 Background and Related Work

Figure 1 illustrates the fundamentals of the most promising emerging memory technologies to be investigated in our project, namely, the Phase-Change RAM (PCRAM), the Magnetic RAM (MRAM) based on Spin-Torque Transfer RAM (STT-RAM), the resistive RAM (RRAM), and the memristor. In this section, we will briefly describe the physical mechanisms of the emerging NVM devices. The research and development related to this proposal will also be described.

#### 2.1 Phase-Change RAM (PCRAM)

PCRAM technology is based on a chalcogenide alloy (typically,  $\text{Ge}_2\text{-Sb}_2\text{-Te}_5$ , GST) material, which is similar to those commonly used in optical storage means (compact discs and digital versatile discs) [4]. The data storage capability is achieved from the resistance differences between an amorphous (high-resistance) and a crystalline (low-resistance) phase of the chalcogenide-based material

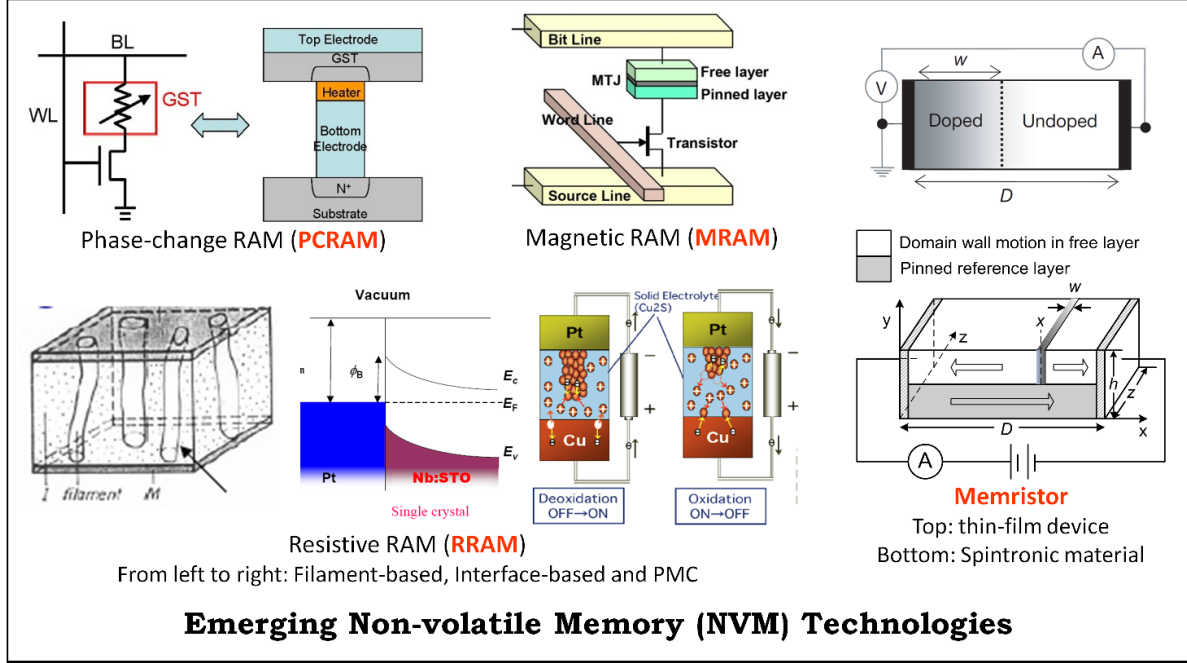


Figure 1: Overview of Some Emerging Non-volatile Memory Technologies, including Phase-Change RAM (PCRAM), Magnetic RAM (MRAM), resistive RAM (RRAM), and memristor.

as shown in Figure 1. In SET operation, the phase change material is crystallized by applying an electrical pulse that heats a significant portion of the cell above its crystallization temperature. In RESET operation, a larger electrical current is applied and then abruptly cut off in order to melt and then quench the material, leaving it in the amorphous state [3].

PCRAM has shown to offer compatible integration with CMOS technology [5], fast speed [6], high endurance [7], and inherent scaling of the phase-change process at 22-nm technology node and beyond [8]. Compared to STT-RAM, PCRAM is even denser with an approximate cell area of  $6 \sim 12F^2$  [1], where  $F$  is the feature size. In addition, phase change material has a key advantage of the excellent scalability within current CMOS fabrication methodology [6, 9–12], with continuous density improvement [13–15].

Although many device models were built from reliability [16], low-frequency noise [17], statistical analysis [18] point of views, they were mainly dedicated to process and device, which cannot be directly borrowed by circuit design and computer community. Many PCRAM prototypes have been demonstrated in the past years by companies like Hitachi [19], Samsung [20], STMicroelectronics [21, 22], and Numonyx [23]. The maximum capacities achieved are 1Gb and 256Mb for single level cell (SLC) [23] and multi-level cell (MLC) [20], respectively. However, to be more competitive to the existing DRAM and Flash memory, PCM need further improvement on density and endurance. In this project, we will address this issue from circuit design point of view.

## 2.2 MRAM based on Spin-Torque Transfer RAM (STT-RAM)

STT-RAM is a new type of Magnetic RAM (MRAM) [1, 24–27], which features non-volatility, fast writing/reading speed ( $<10\text{ns}$ ), high programming endurance ( $>10^{15}$  cycles) and zero standby power [1]. The storage capability or programmability of MRAM arises from magnetic tunneling junction (MTJ), in which a thin tunneling dielectric, e.g.,  $\text{MgO}$ , is sandwiched by two ferromagnetic layers, as shown in Figure 1. One ferromagnetic layer (“pinned layer”) is designed to have its magnetization pinned, while the magnetization of the other layer (“free layer”) can be flipped by a write event. An MTJ has a low (high) resistance if the magnetizations of the free layer and

the pinned layer are parallel (anti-parallel). In first-generation MRAM design, the magnetization of free layer is changed by the current-induced magnetic field [28, 29]. In STT-RAM, a new write mechanism called “polarization-current-induced magnetization switching” is introduced – the magnetization of free layer is flipped by the electrical current directly. Because the current required to switch an MTJ resistance state is proportional to the MTJ cell area, STT-RAM is believed to have a better scaling property than the first-generation MRAM [24, 25, 30–34].

Continuous efforts on process development have been taken on yield improvement [35], write power reduction [36], and high density [37]. Prototyping STT-RAM chips have been demonstrated recently by various companies and research groups [24, 28, 30, 38–40]. Commercial MRAM products have been launched by companies like Everspin (which is a spin-off from Freescale to expedite the technology commercialization in 2008) and NEC.

We have proposed a dynamic MTJ model with more accurate (transient) description for MTJ resistance switching [41]. Compared to highly conceptual fixed resistance used in traditional STT-RAM design flow, the dynamic model can help to reduce 20% pessimism in write time at TSMC  $0.13\mu\text{m}$ . The failure probability of STT-RAM cells due to parameter variations was considered and discussed in [42]. A model was proposed to predict memory yield and design optimization to minimize memory failures. MRAM potentially could be next-generation on-chip cache or memory due to its fast access and soft-error resistance. We will work toward this direction and look for new solutions and more applications to fast this procedure.

### 2.3 Resistive RAM (RRAM)

In an R-RAM cell, the data is stored as two (single-level cell, or SLC) or more resistance states (multi-level cell, or MLC) of the resistive switch device (RSD). Resistive switching in transition metal oxides was discovered in thin NiO film decades ago [43]. From then, a large variety of metal-oxide materials have been verified to have resistive switching characteristics, including  $\text{TiO}_2$  [44],  $\text{NiO}_x$  [45], Cr-doped  $\text{SrTiO}_3$  [46], PCMO [47], and CMO [48] etc. Based on the storage mechanisms, RRAM materials can be cataloged as filament-based, interface-based, programmable-metallization-cell (PMC), etc. Based on the electrical property of resistive switching, RSDs can be divided into two categories: unipolar or bipolar.

Filament-based RRAM is a typical example of unipolar switching [49] that has been widely investigated. The insulating material between two electrodes can be made conducting through a hopping or tunneling conduction path after the application of a sufficiently high voltage. The data storage could be achieved by break (RESET) or reconnect (SET) the conducting path. Programmable-metallization-cell (PMC) [50] is a promising bipolar switching technology. The switching mechanism of PMC can be explained as forming or breaking the small metallic “nanowire” by moving the metal ions between two sold metal electrodes.

#### HL: Related work.

### 2.4 Memristor

Memristor, the fourth fundamental passive circuit element, was predicted by Professor Chua in 1971 [51], based on the completeness of circuit theory. Memristance ( $M$ ) is a function of charge ( $q$ ), which depends upon the historic behavior of the current (or voltage) profile [52, 53]. In 2008, 37 years after memristor was predicted in theory, the researchers at HP reported the first real device of a memristor. The memristive effect was achieved in a solid-state thin film two-terminal device by moving the doping front along the device as shown in Figure 1 [54]. Afterwards, magnetic technology provides the other possible methods to build a memristive system [55, 56]. Due to its unique historic characteristic, memristor has very broad application including nonvolatile memory, signal processing, control and learning system etc [57].

|                                      | SRAM             | DRAM             | NAND Flash          | PC-RAM           | STT-RAM          | R-RAM & Memristor |
|--------------------------------------|------------------|------------------|---------------------|------------------|------------------|-------------------|
| Data Retention                       | N                | N                | Y                   | Y                | Y                | Y                 |
| Memory Cell Factor (F <sup>2</sup> ) | 50-120           | 6-10             | 2-5                 | 6-12             | 4-20             | <1                |
| Read Time (ns)                       | 1                | 30               | 50                  | 20-50            | 2-20             | <50               |
| Write /Erase Time (ns)               | 1                | 50               | 106-10 <sup>5</sup> | 50-120           | 2-20             | <100              |
| Number of Rewrites                   | 10 <sup>16</sup> | 10 <sup>16</sup> | 10 <sup>5</sup>     | 10 <sup>10</sup> | 10 <sup>15</sup> | 10 <sup>15</sup>  |
| Power Read/Write                     | Low              | Low              | High                | Low              | Low              | Low               |
| Power (Other than R/W)               | Leakage Current  | Refresh Power    | None                | None             | None             | None              |

Figure 2: The comparison of various memory technologies [1].

**HL: Related work.** Indeed, HP Labs plan to unveil RRAM prototype chips based on memristor with crossbar arrays soon.

**Summary** Figure 2 illustrates the comparison of emerging memory technologies – PCRAM, MRAM (STT-RAM), RRAM and Memristor – against the traditional main-stream SRAM, DRAM, and NAND-based Flash memory [1].

Note that both CMOS-compatible embedded MRAM (NEC) [58] and embedded PCRAM (Hitachi and STMicro) [19, 59] have been demonstrated, paving the way of integrating these NVMs to the traditional memory hierarchies. In addition, the emerging 3D integration technologies [60, 61] enables cost-effective integration of these NVMs with CMOS logic circuits. With all the NVM technology advances in recent years, it is anticipated that the emerging NVM technologies will break important ground and move closer to market in the near future (“Non-volatile memory goes commercial”, Eetimes, 12/02/2009).

### 3 Proposed Research

To enable the massive production and commercialization of the emerging memory technologies, there are many critical technical issues to be solved. For example, how to introduce the novel devices into the existing design flow? How to minimize the process variation impacts? How to relieve the effect of the poor endurance and improve life time? In this project, we start with the modeling and analysis methodologies for emerging non-volatile memories (NVMs); Next, novel circuitry schemes will be proposed for each emerging NVMs based on their physical characteristics or issues; Finally, we explore novel applications that are enabled by the unique features of emerging NVM technologies. Our proposed research takes a holistic design perspective with close collaboration between two PIs with complementary expertise, aiming at accelerating the adoption of emerging NVMs for future computer architecture design.

#### 3.1 Device Modeling and Design Flow

**HL: Need to be modified.** To help the architectural level and system-level design of the SRAM-based or DRAM-based cache and memory, various modeling tools have been developed during the last decade. For example, CACTI [?, ?, ?, ?] and DRAMsim [?] have become widely used in the computer architecture community to estimate the speed, power, and area parameters of SRAM and DRAM caches and main memory. Similarly, to explore new design opportunities that these emerging memory technologies can bring to the designers at architecture and system levels, it is imperative to have a high-level model for caches and memories built with emerging NVMs, such as MRAM/PCRAM. The model needs to provide the extraction of all important parameters, including access latency, dynamic access power, leakage power, die area, and I/O bandwidth *etc.*,

to facilitate architecture and system-level analysis and to bridge the gap between the abundant research activities at process and device levels and the lack of a high-level cache and memory model for emerging NVMs.

### 3.1.1 NVM Device Modeling

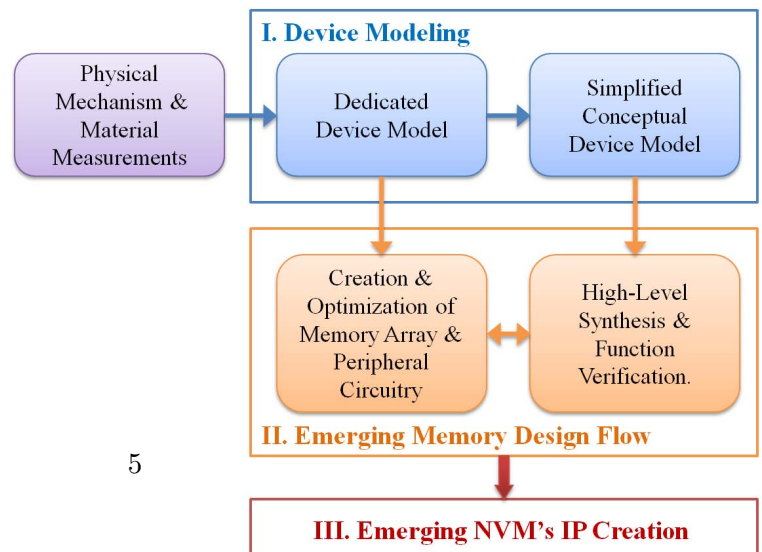
Not like SRAM which is based on traditional CMOS technology, new materials are introduced in the emerging NVM technologies. For example, MRAM arises from magnetic tunneling junction (MTJ), and PCRAM technology is based on  $\text{Ge}_2\text{-Sb}_2\text{-Te}_5$ . Due to the lack of knowledge on material physics of these NVM devices, most of research works on circuit, architecture and system levels nowadays are based on highly-simplified characteristics of the emerging devices. This methodology can cause a large design overhead, increase the production cost, and reduce the design margin, especially in the highly scaled technology with large process variations. For example, the data storage element MTJ at a certain resistance state is usually modeled as a constant resistor by ignoring the dependency of the MTJ resistance on the magnitude of the read/write current driven by the NMOS selection transistor in an MRAM cell. Our previous work [41] showed that after adopting a dynamic MTJ model that can take into account the time-varying electrical inputs in MRAM design flow, the design pessimism can be dramatically minimized and the memory array area can be reduced by more than 40%. Therefore, one of the important tasks of our proposal is to build device models of the emerging NVM technologies for circuit design. Both dedicated device model and simplified behavioral model will be developed.

The dedicated device models, which will be built based on physical mechanism and corroborated by device measurements, need to satisfy three requirements: (1) These models should provide not only the accurate static characteristics (i.e., I-V relationship and high/low resistances), but also the reasonable dynamic behaviors, for example, what is the relationship between write current amplitude and write current pulse width and frequency in PCRAM design? How does MTJ resistance change during the magnetic direction transition of ferromagnetic layer? (2) The device parameter fluctuations induced by process variations, such as line-edge roughnesses (LERs), oxide thickness fluctuations (OTFs), and random discrete dopants (RDDs), will be also analyzed and integrated into the dedicated device model; and (3) the models should have reasonable runtime and be compatible to commercial EDA tools, i.e., HSPICE from Synopsys [?] and Spectre from Cadence. Hence, Verilog-A or C language could be used to implement these models. The dedicated model will be used for memory optimization and timing/power analysis.

On top of it, the simplified behavioral models will be extracted. High-level languages, i.e. VHDL/Verilog or C will be used. The highly simplified conceptual model will be used for logic and functionality analysis.

### 3.1.2 Circuit Design Flow

Another important task of our proposal is to build a design environment that can be seamlessly integrated with the existing CMOS logic design flow. **HL: Modify figure.** Figure 3 illustrates the proposed scope of device modeling and circuit analysis methodology for the emerging NVMs. In Stage I, we will develop the dedicated device models be based on physical mechanism. On top of it, the



simplified behavior models will be extracted. In Stage II, we will build an emerging memory design flow, which can realize the creation and optimization of novel hierarchical memory array structure and peripheral circuitry. The accuracy of the corresponding device model will determine the credibility of the design, such as critical timing/power simulation and corner analysis. Therefore, the dedicated device model will be used in this step. High-level synthesis and function verification will also be an important part in Stage II. The simplified conceptual model is expected to provide sufficient accuracy and can be easily integrated in the commercial EDA tools and design methodologies such as *Primetime* and *Timemill* from Synopsys [?] for more thoroughly analysis, *i.e.*, the critical path timing at design corners. In Stage III, we will build IP's (Intelligence Properties) for emerging NVM technologies with the aid of the proposed design flow in Stage II. The IP's will provide the extracted parameters of memory array cell including area, dynamic and leakage power, access latency, *etc.*, the recommendable memory array structures and the corresponding trade-offs, as well as the optimized peripheral circuitry design, *i.e.*, sense amplifier and write drivers. Those IP's will be used in the researches at architectural and system levels.

The whole methodology and the corresponding outcomes, including device models, memory design flow, and IP's, will be distributed to the architecture and system design community. Our project will build a channel and provide a friendly interface among material development, device fabrication and architecture design.

### 3.1.3 Architectural Modeling

Based on the device/circuit-level modeling and analysis methodologies described in Task 1-A, we will develop a PCRAM/MRAM simulator, which can be easily integrated with architecture simulators including SimpleScalar-based single core simulator [?, ?], and multi-core simulators such as M5 [?], GEMS [?] or PTLsim [?].

Note that tools such as CACTI [?, ?, ?, ?] and DRAMsim [?] have been widely used in the computer architecture community to estimate the speed, power, and area parameters of the traditional caches and main memory. However, these existing tools were initiated and built based on the cache and memory modelings of SRAM/DRAM. The architectural modeling for PCRAM/MRAM raises unique research issues and challenges on building such simulators. First, some circuitry modules in PCRAM/MRAM have different requirements from those originally designed for SRAM/DRAM. For example, the existing sense amplifier model in CACTI [?, ?, ?, ?] and DRAMsim [?] is voltage-mode sensing, while PCRAM data reading usually uses a current-mode sense amplifier. Second, due to the unique device mechanisms, the models of PCRAM/MRAM need specialized circuits to properly handle their operations. We can still take PCRAM as an example. The specific pulse shapes are required to heat up GST material quickly and to cool it down gradually during the RESET and especially SET operations. Hence, a model of the slow quench pulse shaper need to be created. Finally, the most obvious and important difference between PCRAM/MRAM and SRAM/DRAM is their distinct memory cell structure. PCRAM and MRAM typically use a simple "1T1R" (one-transistor-one-resistor) or "1D1R" (one-diode-one-resistor) structure, while SRAM and DRAM cell has a conventional "6T" structure and "1T1C" (one-transistor-one-capacitor) structure, respectively. The difference of cell structures directly leads to different cell sizes and array structures.

In addition, where to place these NVM memories in the traditional memory hierarchy also influences the modeling methodologies. For example, the emerging NVMs could be used as a re-

placement for on-chip cache or for off-chip DIMM (dual in-line memory module). Obviously, the performance/power of on-chip cache and off-chip DIMM would be quite different: When a NVM is integrated with logics on the same die, there is no off-chip pin limitation so that the interface between NVM and logic can be re-designed to provide a much higher bandwidth. Furthermore, off-chip memory is not affected by the thermal profile of the microprocessor core while the on-chip cache is affected by the heat dissipation from the hot cores. While higher on-chip temperature has a negative impact on SRAM/DRAM memory, it actually has a positive influence on PCRAM because the heat can facilitate the write operations of PCRAM cell. The performance estimation of PCRAM becomes much more complicated in such a case. Moreover, building an accurate PCRAM/MRAM simulator needs close collaborations with the industry (see collaboration letters from HP, IBM, IMEC, and Seagate) to understand physics and circuit details, as well as architectural level requirements such as the interface/interconnect with the multi-core CPUs.

#### **3.1.4 Preliminary Result and Collaborations:**

The PI Li has built a combined magnetic and circuit design analysis and optimization methodology for MRAM, which has been proved to improve design efficiency significantly [41] by test-chip design and fabrication at Seagate. We are also one of the first researchers to propose spintronic memristor structures [56], which was interviewed by IEEE Spectrum [?]. The corresponding compact model and corner analysis [57] have also been developed. In this project, we will further extend this methodology to other emerging NVMs, such as PCRAM.

The PSU PI Xie has developed a stacked SRAM cache simulator called 3DCacti [?, ?], which has been widely downloaded and used by other researchers. The PI and co-PI have collaborated together when the PI Li was in Seagate, to develop a preliminary version of MRAM simulator for cache stacking [?, ?]. Xie also collaborated with Dr. Norm Jouppi from HP Labs, developed a preliminary version of PCRAM simulator [?]. We will extend our tools to support architectural exploration in Task 2, especially for hybrid memory systems with an emphasis on multi-core architecture (for example, interface design and coherency modeling) and with Non-Uniform Cache Architecture (NUCA) model (for large memory). Dr. Norm Jouppi from HP Labs, with his expertise in memory architecture modeling, will keep a close collaboration with us for the development of the architectural models for NVMs (see supporting letter from Dr. Jouppi), and we will integrate our models to HP Labs' CACTI tool [?], which is an integrated cache and memory model that is widely used in computer architecture community for design space exploration.

### **3.2 Explore novel circuit techniques for NVM**

The advent of novel materials and devices have introduced a number of new design issues. On one hand, all types of emerging NVM technologies are facing to the common requirements – fast speed, high density, affordable yield, low power, etc. On the other hand, the primary concern and effective solution could be quite different for each NVM technique because of the specific device characteristic and process integration difficulty. Our task here is to investigate the common design issues and to exploit distinctive circuit techniques for each individual emerging NVM technology. More specifically, we will focus on three main issues in memory design – yield, reliability, and density.

#### **3.2.1 Write Endurance Improvement**

Write endurance is one of the biggest obstacles that prevent the emerging NVMs from massive production and wide application, although the physical mechanisms behind for various emerging NVMs are different. For PCRAM, writing is the primary wear mechanism: when injecting current into a volume of phase change material, thermal expansion and contraction degrades the electrode-



storage contact [?]. While in MRAM, the cell damage during write operations mainly is triggered by particles and pin-holes introduced in process integration. Write endurance is usually measured as the number of writes performed before the cell cannot be programmed reliably. SRAM and DRAM both have endurance of about  $10^{16}$  programming cycles [1], which are sufficient for use even in high-performance processing. The best reported write endurance for PCRAM, however, is only  $10^9$  based on a survey of PCRAM device and circuit prototypes published within the last five years [?]. And the best endurance test result of STT-RAM is less than  $4 \times 10^{12}$  programming cycles [31].

Besides the improvements on device material and process development, the most straightforward and effective approach is to reduce the time period that writing current applied on the memory cell. Some architectural level solutions have been proposed previously, such as early write termination [?] or partial writes [?]. Circuit design can also help out in many ways. For example, An accurate self-timing control scheme is necessary, which can stop providing writing current to memory cells once detecting successful set/reset operations. Because the damage on NVM material has an exponential relationship with the current/energy applied on it, one possible solution is smoothing the driving current during write operation and avoiding overshoot on NVM materials. Here, how to design a write driver to provide a sleek but fast ramp-up curve is the tricky part. Another interesting alternative could be lowering the voltage on memory device to meet only the minimal current requirements. Then, how to overcome process variation and even utilize it to control driving current are two key challenges. Furthermore, for some applications that non-volatility is not a requirement (i.e. directly replace SRAM with PCRAM), we can even trade data retention with endurance by further reducing the energy pulse. Of course, the statically or dynamically fixing by using redundancy and ECC will keep useful. However, will the more complex ECC algorithms or bit-level redundancy be needed? This project will investigate these solutions and give convincing answers.

Multi-level cell (MLC) can effectively improve the integration density of memory by storing more than one bit information in a single memory device:  $n$  bits are represented by  $2^n$  states of a storage device. MLC technology has achieved significant commercial success in NAND flash memory [?] and it has been explored in PCRAM [4, 12], STT-RAM [37], and RRAM [?]. It can effectively improve the integration density of memory. However, the write endurance is also degraded due to the smaller resistance gap between two adjacent states.

Figure 4 shows the transition distribution between the different logic values of 2-bit MLC in an in-order microarchitecture. We noticed that most of transitions occur between the same values, and hence, there is no need to change resistance state at all. Therefore, “write-after-read” scheme, which conducts only the necessary transitions based on the values of the new data being written and the original data stored in the MLC bit, could be the most efficient way for energy saving and lifetime improvement. Furthermore, we observe that the resistance switching in MLC need follow specific sequence. For example, the free layer of the MTJ in an MLC MRAM has two magnetic domains whose magnetization directions can be switched separately. The magnetization direction of *soft domain* can be switched alone by a small current, while that of *hard domain* can be switched by only a large current which is always associated with the magnetization direction

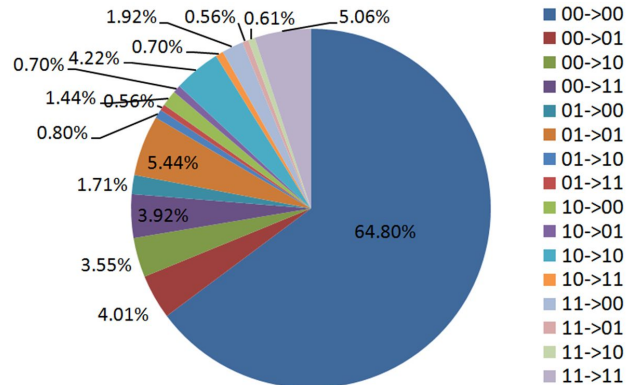


Figure 4: The transition distribution between the different values of MLC MRAM bit



switching of soft domain. Corresponding to the four resistance states –  $R_{00}$ ,  $R_{01}$ ,  $R_{10}$ , and  $R_{11}$  from low to high, an MLC MRAM cell may have total of  $4! = 24$  encoding schemes for its four logic states –  $L_{00}$ ,  $L_{01}$ ,  $L_{10}$ , and  $L_{11}$ . As we stated above that the probability of MTJ breakdown has an exponential relationship with the current amplitude through it, the hard domain switching can induce more damage on MTJ material than the soft domain switching. Properly selecting the encoding scheme of logic vs. physical states to reduce the hard domain switches based on the transition distributions can further improve the write endurance and lifetime of MLC MRAM.

### 3.2.2 Process Variation-Tolerant Design

As the process technology scales, device parameter fluctuations induced by process variations such as line-edge roughnesses (LERs) and oxide thickness fluctuations (OTFs) have become critical issues in affecting the performance of devices [?]. Similar to any other memory manufactured in the scaled technologies, emerging nonvolatile memories also suffer from the large process variation. For example, MTJ resistance increases exponentially with the thickness of oxide barrier between two magnetic layers. It was reported in [?] that MTJ resistance increases by 8% when the thickness of oxide barrier changes from  $14\text{\AA}$  to  $14.1\text{\AA}$ . Moreover, the MTJ resistance variation will be aggravated by the further reduction of oxide barrier thickness in scaled technologies. Besides oxide barrier thickness, MTJ resistance is also significantly affected by the large MTJ geometry variations.

**Read Failure** Most of the emerging NVM technologies, e.g., MRAM and PCRAM, use device resistance as the data storage media. **Figure xxx(a)** illustrates a conventional voltage sensing scheme: Comparing the bit line voltage  $V_{BL}$  generated by the selected memory cell with a reference signal  $V_{REF}$  produced by the dummy cell. Ideally the resistance of the dummy cell should be set in the middle of the high and low resistance states ( $R_H$  and  $R_L$ ) of the selected memory cell. When  $V_{BL}$  is higher than  $V_{REF}$ , the data storage device in the memory cell is in  $R_H$  state, and vice versa. Usually a dummy cell is shared by multiple memory bits to reduce overhead. In reality, process variation incurs the resistance distribution of data storage device in memory cell as well as the dummy cell. As illustrated **Figure xxx(b)**, when the resistance variation  $\sigma_R$  is large, the tails of  $R_H$  or/and  $R_L$  could be overlapped with  $R_{dummy}$  and lead to the false detection of the stored value. We called it as **Read Failure**.

Read failure is a severe problem in STT-RAM design for two main constraints. (1) The difference between two resistance states of MTJ is fairly small:  $\Delta R = R_H - R_L \approx 1000\Omega$  at 45nm technology node [42]; and (2) the MTJ resistance variation  $\sigma_R$  is relatively high because it is extremely difficult to control oxide barrier thickness within a small range of variation, i.e.  $0.5\text{\AA}$  [?]. Besides the regular yield improvement techniques, such as redundant column/row and ECC (Error Correction Code), a self-reference read-out scheme could be another effective way to fix read-failure problem.

The basic idea of a self-reference reading is to compare the stored data in a memory cell with a reference value written to the same cell. By limiting the comparison within one single STT-RAM cell, the impact of bit-to-bit variation of MTJ resistance can be avoided. Previously some self-reference schemes were used in toggle-mode MRAM design [?, ?]. We also successfully utilized it in STT-RAM design [?]. These schemes are all “destructive” because the original value in memory cell is wiped out when writing the reference value into MTJ, and has to be recovered at the end of the read operation. Obviously it prolongs read latency and introduces reliability issue.

In this project, we will work on a **non-destructive self-reference** methodology, which does not disturb the original data during read operations. The approach comes from the special R-I characteristic of MgO-based MTJ. As we can see in Figure 5, the MTJ current dependence of the high and the low resistance states are quite different:

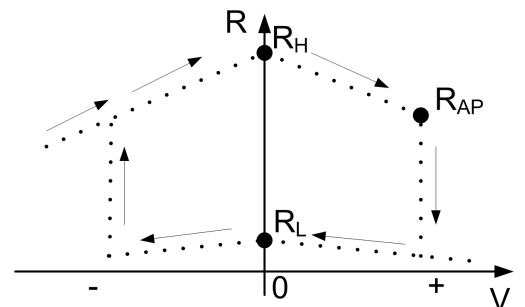


Figure 5: The static R-I curve of MgO-based MTJ. **HL: Modify Figure**

the current roll-off slope of high resistance is much steeper than that of low resistance. Therefore, we can sample the stored value of an MTJ twice by using two read currents  $I_{R1}$  and  $I_{R2}$  and compare the resistance difference  $\Delta R = R1 - R2$ . Obviously  $\Delta R_H$  is pretty big, while  $\Delta R_L$  is close to '0'.

However, there are some uncertainties to realize this approach. For example, how much is the sensing margin in the new read-out scheme after considering process variations? What type of sensing circuitry is more optimal? Will a new sense-amplifier (SA) design be necessary? How does it impact memory array structure? How much yield improvement can be achieved with the new scheme? Will this scheme be still valid when technology further scales down? In this proposal we will investigate these issues and exploring the solutions. Our target is to minimize the effect of process variation and to improve read speed.

**dopant drifting in Memristor, read window change???** HL: Add new section here. Process has more impacts on memristor-based design, especially when memristor is used for a continuous data storage and detection.

### 3.2.3 Density Enhancement

Memory density is directly related to its capacity, and hence, reducing memory cell size and increasing density becomes an ultimate goal. In the past, technology scaling is always the biggest driving force to reduce single memory cell size by decreasing the pattern on chip. Process development plays an important role as well. For example, the charge storage materials of NAND Flash have gone through several generations to continue its scalability: from standard double polysilicon gate, to Silicon-Oxide-Nitride-Oxide-Silicon (SONOS), to bandgap engineered SONOS, and to TaN/Al<sub>2</sub>O<sub>3</sub>/SiN/SiO<sub>2</sub> (TaNOS) [?]. The emerge of new NVMs is another good example to show the power of technology. On top of it, we should note that cell structure and circuit design technique can also constraint or boost memory density.

**MRAM and PCRAM** In a random access memory cell, usually an NMOS transistor is used as selection device (e.g. DRAM, MRAM and PCRAM) by connecting it in series with the data storage element. Such a cell structure needs three sets of terminals – word line (WL), bit line (BL) and source line (SL). The routing requirement and design rules determine that the minimal possible cell size is  $12F^2$  [42]. Here,  $F$  represents the technology feature size.

The real memory size is also determined by ... The real cell size could grow when the storage device cannot fit into it or the select transistor need serve as driving device too.

**RRAM and Memristor** Theoretically, the smallest memory cell is  $4F^2$ , which has only two terminals – one is horizontal (WL) and another is vertical (BL). The storage element is built at the cross-point of two metal wires, so it is called cross-point structure. RRAM can support data access in this structure by properly controlling the voltages applied on WL's and BL's. Moreover, the cross-point structure can grow in third dimension and forms an intra-die stacking structure. The memory storage cell is located in between any two adjacent metal layers which are used as interconnects. Within the same die size, the multiple memory layers further improve the memory density. Hence, RRAM is expected to replace NAND Flash memory as main storage in near future [1].

From design point of view, RRAM technologies can be divided into two operation types: unipolar switching and bipolar switching. Unipolar operation executes the programming/erasing by using short and long pulse, or by using high and low voltage with the same voltage polarity. Usually a diode is served as selection device (1D1R). The data in bipolar switching RRAM can be changed

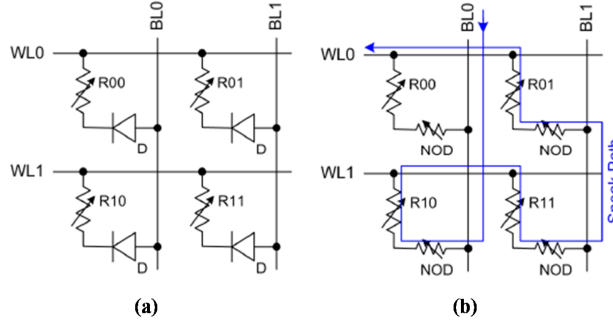


Figure 6: RRAM memory cell scheme. (a) 1D1R; (b) 1NOD-1R.

by short voltage/current pulses with opposite voltage polarity. For such memory structures, non-ohmic device (NOD) [?] is used to provide two-direction driving current as well as support process integration of cross-point structure. We call it as 1NOD-1R (See Figure 6).

However, 1D1R and 1NOD-1R cell structures are facing on some design difficulties due to process limitation. Conceptually, NOD can be understood as two parallel connected diodes. Ideally, it turns on only when the voltage drop between the two terminals exceeds its threshold. However, the I-V characteristic curve of real device could be quite different. This results in sneak path which has three or more cells in series as shown in Figure 6(b). The sneak current can introduce disturbance on unintended cells during read, write and erase operations. Therefore, diode (P-N or Schottky) is more favorable as a selective element for RRAM array and intra-die stacking. However, it is extremely difficult to achieve the high quality diode with large  $I_{on}/I_{off}$  ratio (large forward current  $I_{on}$  and extremely small reverse current  $I_{off}$ ) by using temperature limited BEOL (back end of line) process ( $< 400^\circ C$ ) [?].

**Using bipolar PMC as the selective element.** We propose to bipolar resistive switching devices as the selection device. Programmable-metallization-cell (PMC) could be a good candidate. PMC [50] is a promising bipolar RRAM technology, which is composed of two solid metal electrodes – relatively, one is inert and the other is electrochemically active. Between the two electrodes locates a thin electrolyte film. When a negative bias is applied to the inert electrode in programming operation (SET), metal ions in the electrolyte together with those flew from the positive active electrode can be reduced by the inert electrode. As a result, the metal ions form a small metallic “nanowire” between the two electrodes, which produces a low resistance. In erasing operation (RESET), a positive bias is applied on the inert electrode. Metal ions migrate back into the electrolyte and eventually to the negatively-charged active electrode. The “nanowire” is broken and the resistance increase back. The I-V curve is illustrated in Figure ??(a). A higher voltage is required in RESET operation ( $V_r$ ) than the one in SET operation ( $V_s$ ).

Compared to diode or NOD, PMC based switch has two advantages – bipolar switching and large  $I_{on}/I_{off}$  ratio. Hence, the proposed scheme could be used in bipolar switching RRAM design with minimized sneak current. Although we have investigate the feasibility based on theoretical analysis, there are still a lot of unsolved issues. For example, how to control timing and applied voltage? What kind of peripheral circuitry floorplan will be optimal for the proposed RRAM design? And again, how will process variations affect the proposed RRAM scheme? In this project, we will address these circuit issues from both device and circuit point of views and explore the solutions.

### 3.2.4 Preliminary results and Collaborations:

Previously, we have already successfully utilized the destructive self-reference scheme in STT-RAM design [?]. The feasibility of the non-destructive self-reference scheme has been also discussed and analyzed in theory [?]. Add experience on SRAM design??

## 4 Broader Impacts, Outreach, and Education

**Research Impact and Technical Merit:** Memory hierarchy design is one of the key components in modern computer systems. The importance of the memory hierarchy increases with the advances in performance of the microprocessors [1]. A key *transformative aspect* of the proposed research is that the success of the project will result in innovations in the computer architecture, potentially leading to better performance, higher energy-efficient, and more reliable computer systems.

**Collaborations and Partnership:** It is naturally important to have industry support and guidance for this research. The NYU-Poly PI Li has been with industry for 5 years before joining academia. She has a strong connection with Memory Product Group at Seagate, where she did research and led a design team on nonvolatile memories. The PSU PI Xie worked for IBM Microelectronics division before joining academia, and has built a good relationship with IBM research. In the past 6 years as a faculty member, Xie has close collaborations with industry partners. The proposed research has intrigued our industry partners, and the project will be carried out with close collaboration with partners in several companies, including IBM, Intel, HP, IMEC, Qualcomm, and Seagate (supporting letters are included in the supplement documents section). The investigators anticipate that the techniques and tools developed in this project will be used in both classroom projects and academic/industrial research. We will closely work with our industry partners to transfer research results into commercial designs. The proposed technology is of immense interest for companies.

**Outreach and Knowledge Dissemination:** As part of outreach efforts, the PIs will actively disseminate results to a wide audience and to different professional communities. The NYU-Poly PI Li believes that the communication between academia and industry is very important. In NANOARCH 2009, she organized a panel on Emerging Technologies, which brought industrial voices into emerging NVM research. The PSU PI Xie has delivered over 30 invited talks in the past at IEEE Chapters, universities, and companies. He has been a tutorial speaker at several forums, offering tutorials on 3D ICs in MICRO 2006, ISCA 2008, GLSVLSI 2008, and MICRO 2009 [?]. Penn State is part of the University-Industry-Government partnership called The Technology Collaborative (TTC) that focuses on research, training and education issues related with system design. The PI from Penn State has been actively involved with their education programs and have offered courses to the local industry in the past through TTC. We will use this forum to disseminate findings of the proposed research to industry practitioners, who in turn can facilitate technology transition and incorporate research breakthroughs in real systems.

**Women and Minority Student Recruiting Activities** While this research program will make contributions in educating all students to be well prepared for designing future computer systems, it will make additional efforts to promote diversity. Being a woman faculty herself, the NYU-Poly PI Li plans to actively recruit and mentor women and minority students. The PSU PI has an impressive record of graduate student advising, especially those from underrepresented groups, having graduated several women and minority graduate students. The PIs will continue to attract underrepresented students by getting their current graduate students from underrepresented communities to present their research at minority undergraduate institutions and to serve

as role models. The PIs have been working with women and minority recruiting programs in both universities, i.e., the Multicultural Education and Programs at NYU-Poly and the WISER (Women in Science and Engineering Research) and MURE (Minority Undergraduate Research Experience) programs at PSU.

**Integration with Education:** This project will involve graduate and undergraduate students in all aspects of the research. The PIs, as in the past, will actively integrate the research results from this project into the graduate and undergraduate curricula, especially related to computer architecture. The NYU-Poly PI teaches a graduate-level course EL5473 (Introduction to VLSI), and this project will allow the PIs to integrate additional practical material to make the class more appealing for engineering students. A graduate-level course on advanced topics in computer architecture will be developed at NYU-Poly in collaboration with colleagues who are experts in architecture and circuit design. Undergraduate students will be especially targeted and encouraged to pursue graduate studies. Support for undergraduate researchers will also be sought from NSF REU supplements and by involving the outstanding students from the Schreyers Honors program at Penn State. Beyond involving students in all aspects of research, the PIs will develop new courses on different aspects of advanced computer architecture and VLSI, to train the next generation work-force. In addition, the PIs plans to organize workshops and tutorials at major conferences to support other faculty to adapt new teaching and research material in their curricula. Class notes, slides, and laboratory manuals related to the new courses developed will be made publicly available. The PIs will educate industrial practitioners and use this grant to disseminate findings to industry practitioners, who in turn can facilitate technology transition and incorporate research breakthroughs in real systems.

**Collaborative Teaching Experiments:** A graduate-level course on emerging non-volatile memories will be simultaneously offered at Penn State and NYU-Poly (in a *virtual classroom*) through an online course delivery system (WebEx). Lectures will originate from both schools based on the topics to be covered. The PIs will incorporate the latest research outcomes from this project. Students at PSU and NYU-Poly will also experiment with the tools developed as a part of this research. This multi-institution education plan will not only provide a unique opportunity for students to learn from experts in other universities/areas but also promote collaborations among students in different schools through working together on course projects. Such remote collaboration is a critical skill in today's global economy, where many companies have offices throughout the world.

**Training of Students:** Student mentoring is a key component of this project. The PSU PI has excellent records in student training. His mentoring efforts were recently recognized with two Ph.D. students winning the department's "Best Research Assisant Award" in 2008 and 2009. He has graduated 3 Ph.D. students (one in Sun Microsystem, one in Qualcomm, and the other one in TSMC). His students have received one best paper award (in ASPDAC 2008), and three best paper award nominations (in ICCAD 2006 and ASPDAC 2009, 2010). The NYU-Poly PI just starts her academia career recently in Fall 2009. She will be getting advice from the PSU PI on how to mentor and train graduate students during the course of this 3-year project.

## 5 Project Management and Industry Collaborations

The research team poses complementary skills required for the project. The PIs are well qualified for the proposed research with significant prior experience in various areas. The PI Prof. Li has 5-years industrial experience related to device modeling and circuit design with focus on emerging non-volatile memories, and just recently joined NYU-Poly as an assistant professor. The co-PI Prof. Xie's expertise span areas of VLSI and architecture, with extensive experience in architectures with

emerging technologies, such as 3D architecture. The PIs will work in close coordination on different parts of this project. The integration of all these research components and tool will be a coordinated effort by all the investigators. The project is a three-year effort involving multiple PhD students. Li will lead the effort in the first year with 2 PhD students from NYU working with 1 PhD student from PSU on the circuit and architectural modeling in Task 1. In the second year, Xie will lead the effort in Task 2, with 2 PhD students from PSU and 1 student from NYU, to study architectural techniques using NVM technologies. In the final year, both PIs will work together with 1 PhD from each institute to study novel applications that leverage NVM technologies. Detailed project milestones are given in Figure 7.

|                        | Year 1   | Year 2       | Year3       |
|------------------------|----------|--------------|-------------|
| Task 1 (GRA1 & 2 & 3 ) | Modeling |              |             |
| Task 2 (GRA 3 & 4 & 1) |          | Architecture |             |
| Task 3 (GRA 3 & 4)     |          |              | Application |
| # of Students          | NYU: 2   | NYU: 1       | NYU:1       |
|                        | PSU: 1   | PSU: 2       | PSU: 1      |

GRA1 and 2: NYU students, GRA3 &4: Penn State students

Figure 7: Project Management (The first student in each task would be the lead).

The PIs have a well-established collaboration in the past years, when the PI was still in Seagate, and published preliminary results on NVM architectures in DAC 2008 and HPCA 2009 [?, 61]. The existing collaboration and preliminary results will allow rapid ramp-up for the proposed research. The two teams will coordinate with each other via weekly teleconferences and regular mutual visits (with only 4-hour driving between two institutes).

**Industry Collaborations.** By leveraging both PI’s past industry experience and successful collaborations with companies, the project will be carried out in close collaboration with industrial partners from IBM, HP, Intel, Qualcomm, Seagate, ITRI, as well as with a partner from IMEC in Belgium (see attached supporting letters). The industrial collaborators will play important roles in the proposed project by enabling the acquisition of realistic data, discussion of the practicality of ideas, placement of students in internships and permanent positions, and eventually the transfer of the technologies. By working closely with researchers in industry, the PIs will be able to ensure that the proposed methodologies and tools are practical and have a real impact on industry.

## 6 Results from Prior NSF Support

**Hai (Helen) Li** recently just joined NYU-Poly as an assistant professor, after 5-years industrial experience in Qualcomm, Intel, and Seagate. She doesn’t have any NSF grant yet.

**Yuan Xie:** The most related prior NSF grant is CCF-0903432 (ADAM: Architecture and Design Automation for 3D Multi-core Systems; 08/2009-07/2012; \$480K). This project aims at developing architectural design techniques and design automation tools for future 3D multi-core architectures. Xie actively collaborates with industry in 3D IC design research (IBM, Qualcomm, Honda, and Seagate). He has published extensively in the 3D IC design and 3D architecture areas, covering various aspects, including 3D architecture [?, ?, ?, ?, ?, ?, ?, ?, 61] and 3D EDA tools [?, ?, ?, ?, ?, ?, ?, 60].

One of the benefits for 3D integration technologies is the capability of enabling cost-effective heterogeneous integration, which makes it much more practical to integrate emerging NVM with CMOS logic circuits. Consequently, the research plan described in this proposal will complement and be synergistic with the ongoing project.

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